

Title (en)

THIN FILM COATING SYSTEM AND METHOD

Title (de)

DÜNNFILMBESCHICHTUNGSSYSTEM UND VERFAHREN

Title (fr)

SYSTÈME ET PROCÉDÉ DE REVÊTEMENT DE FILM, MINCE

Publication

**EP 2220263 A1 20100825 (EN)**

Application

**EP 08841116 A 20081027**

Priority

- US 2008012170 W 20081027
- US 99606307 P 20071026

Abstract (en)

[origin: WO2009055065A1] A method and system for depositing a thin film on a substrate. In the system a target material is deposited and reacted on a substrate surface to form a substantially non- absorbing thin film. The volume of non-absorbing thin film formed per unit of time may be increased by increasing the area of the surface by a factor of "x" and increasing the rate of deposition of the target material by a factor greater than the inverse of the factor "x" to thereby increase the rate of formation of the volume of non-absorbing thin film per unit of time.

IPC 8 full level

**C23C 14/50** (2006.01); **C23C 14/34** (2006.01)

CPC (source: EP)

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Designated contracting state (EPC)

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Designated extension state (EPC)

AL BA MK RS

DOCDB simple family (publication)

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